

# A Digital Hygrometer

HIROMI SHIMIZU, HIROKI MATSUMOTO, STUDENT MEMBER, IEEE, MASAHIRO ASAKURA, AND  
KENZO WATANABE, SENIOR MEMBER, IEEE

**Abstract**—A digital hygrometer using a polyimide capacitive humidity sensor is developed. The capacitance change of the sensor due to adsorption of water vapor in the atmosphere is detected by a switched-capacitor digital capacitance bridge controlled by a one-chip microcomputer and is displayed as relative humidity with 0.1-percent resolution. The accuracy of the hygrometer calibrated by a two-point method is solely determined by the temperature dependence and the long-term drift of the dielectric sensitivity of the sensor and is estimated to be 2 percent.

## I. INTRODUCTION

**A**IR EXPANDS with humidity. This well-known physical phenomenon has been widely used as a hygrometer in daily life, but is not applicable to automatic humidity control of industrial, agricultural, and our living environments because it fails to provide an electrical signal. Among many electronic humidity sensors now being developed [1], a conductive-type sensor using a metal oxide or a ceramic and a capacitive-type sensor using a polymer film are promising candidates for low-cost mass production. The conductive sensors tolerate a high temperature environment, but suffer from a large temperature dependence and their sensitivity to pollution [2]–[4]. Therefore, the capacitive type seems preferable for accurate and stable humidity measurement at room temperature.

Typical hygroscopic materials used so far for sensing moisture in capacitive sensors are lithium-fluoride [5], cellulose acetate [6], and cellulose acetate butyrate [7]. While these hydrophilic films offer high sensitivity, their dielectric constants are sensitive to temperature and their capacitance change with humidity is highly nonlinear because of their nonuniform adsorption isotherm. Compared with them, the “dielectric sensitivity”, i.e., the relative absorption of water vapor, of polyimide is rather small, but is much less sensitive to both temperature and thickness [8], [9]. In addition, good linearity can be expected between the bulk capacitance and relative humidity (RH) [10], [11]. Based on these predecessors' works, we have developed a linear humidity sensor. Its configuration and characteristics are described in the next section.

The capacitance change of the sensor due to RH is small compared with its offset capacitance. Therefore, accurate

detection of RH and converting it to a microprocessor compatible signal require a capacitance bridge followed by an analog-to-digital (A/D) converter. Building such an interface using off-the-shelf components is possible, but is impractical from the viewpoint of the yield and the performance/price ratio. To accomplish the same function with a much simpler circuit and with an eye toward the possibility of on-chip signal conditioning, the digital capacitance bridge is developed based on a switched-capacitor charge-balancing A/D converter [12]. The digital circuitry for controlling this capacitance bridge can be easily implemented using standard logic gates, but a one-chip 8-bit microcomputer is used instead to accommodate other functions. This microcomputer-controlled interface is described in Section III.

Although the capacitance of the sensor changes linearly with RH, its offset capacitance and sensitivity differ from device to device. Therefore, two-point calibration is necessary for direct reading of RH. The calibration procedure and the overall performance of the digital hygrometer are discussed in Section IV. The paper concludes in Section V with the brief summary and the future work.

## II. HUMIDITY SENSOR

The humidity sensor consists of a polyimide capacitor fabricated on a silicon substrate. The use of a silicon as a substrate offers the possibility of integrating the signal processing circuit and thus developing a “smart sensor”. The fabrication procedure is as follows: First, Au is evaporated onto one surface of a 0.001  $\Omega$ -cm, n-type Si wafer 350  $\mu\text{m}$  thick and is sintered at 650°C for 10 min to make the contact ohmic. After removing a SiO<sub>2</sub> layer on the other surface by chemical etching, the polyimide is spun onto a Si surface at 3000 rpm for 30 s. The polyimide film is prebaked at 200°C for 1 h and then cured at 350°C for 1 h. The hygroscopic film thus fabricated is typically 1.5  $\mu\text{m}$  thick. Then, Au is evaporated onto the film through a metal mask to form a moisture-permeable, comb-like electrode. The thickness is typically 500 Å. A thin polyimide film less than 1  $\mu\text{m}$  thick is again coated all over the surface, except the bonding pads, by dipping to protect the hygroscopic film from mechanical damage in the subsequent bonding and packaging process. This wafer is then scribed into chips measuring 8 mm  $\times$  12 mm. The configuration of the humidity sensor thus fabricated is shown in Fig. 1. Finally, each chip is mounted in a perforated metal header through which the sensor is exposed to the atmosphere.

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H. Shimizu and M. Asakura are with the Research and Development Division, Kurabe Industrial Co. Ltd., Kamimura, Hamana 432, Japan.

H. Matsumoto and K. Watanabe are with the Research Institute of Electronics, Shizuoka University, Hamamatsu 432, Japan.

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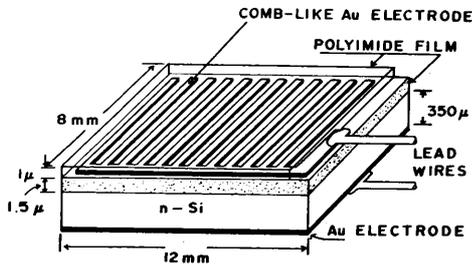


Fig. 1. The structure of the humidity sensor.

The bulk capacitance between the upper/comb-like and lower electrodes was measured over a humidity cycle from 20- to 90-percent RH and a temperature range from 15°C to 35°C. The accuracy of the reference hygrometer attached to the humidity-controlled environmental chamber is 3 percent. A commercially available four-terminal-pair bridge<sup>1</sup> was used for the capacitance measurement over the frequency range from 200 Hz to 500 kHz. Typical results measured at 10-kHz frequency are plotted in Fig. 2. No hysteresis was observed. As expected, a good linearity with a nonlinearity error of less than 0.2-percent and small temperature-dependence less than 0.1-percent RH/°C can be seen. The positive temperature coefficient is considered due to the thermal expansion of the film which allows more water to permeate the film. The dielectric sensitivity defined as the relative change in the capacitance for a unit change in RH is 3100 ppm, which is a typical value of the polyimide film cured at 300°C [10]. The capacitance decreases slightly with the increase in measurement frequency while keeping the sensitivity and the linearity constant [9]. The response time for the step change from 20- to 90-percent RH was about 5 s and that for the reverse change was about 7 s. These results indicate that the comb-like electrode is permeable to moisture and thus the response time is determined solely by diffusion through the film thickness.

Figure 3 shows the long-term stability tested for 8 weeks in various environments. During the first week of accelerated aging at 40°C and 90-percent RH, the sensor exhibited a rapid increase in the capacitance until it settled down to the steady-state value. The steady-state capacitance increases slightly when the sensor is exposed to a hot and wet atmosphere for a long period and decreases slightly when exposed to a hot and dry atmosphere for a long period. The fluctuation is, however, less than 2-percent RH. Therefore, the present sensor has proven its capacity for accurate and reliable RH measurement in the ordinary environments encountered in our daily life.

### III. HYGROMETER CONFIGURATION

The whole circuit diagram of the digital hygrometer is shown in Fig. 4. It comprises three main blocks; the humidity sensor represented by  $C_X$ , the interface consisting of the capacitance bridge and the comparator  $A_2$ , and the one-chip 8-bit microcomputer. The humidity sensor has,

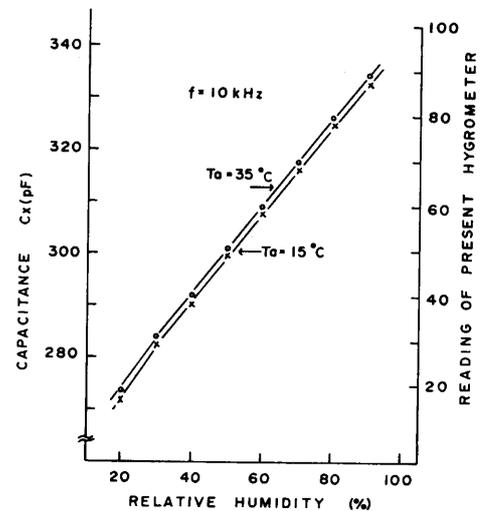


Fig. 2. The sensor capacitance  $C_X$  versus relative humidity (RH).

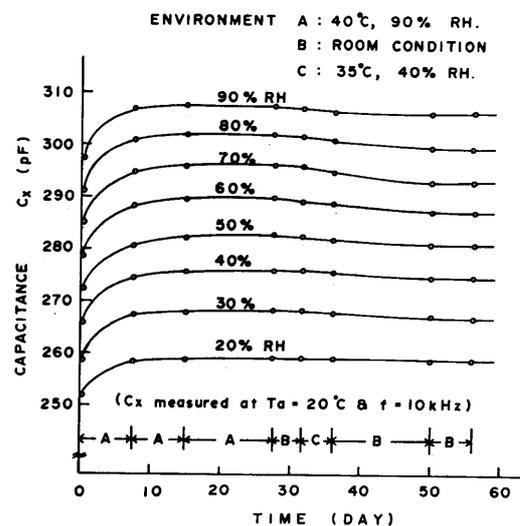


Fig. 3. The capacitance change of the sensor observed in the long-term test.

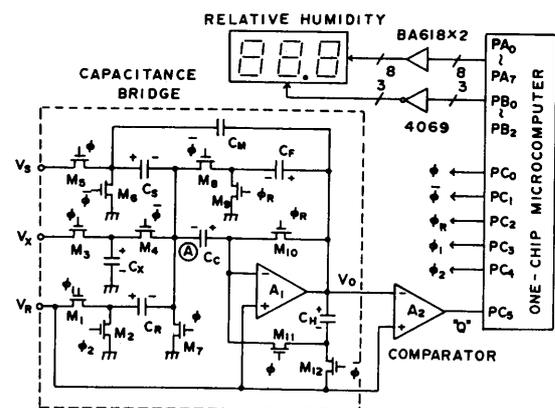


Fig. 4. The circuit diagram of the digital hygrometer.

in fact, the resistive component which should be connected in parallel with  $C_X$ . Because of the high volume-resistivity of polyimide, however, this parallel resistance is large enough to be neglected.

In the bridge,  $C_S$  is a standard capacitor to which  $C_X$  is compared. The difference between them is encoded into an  $n$ -bit binary number with reference to  $C_R$ . The capacitor  $C_F$  incorporated into the feedback path of op-amp  $A_1$

<sup>1</sup>HP Model, 4275A, Multifrequency LCR Meter.

corresponds to a detection arm of a conventional bridge. Capacitors  $C_C$  and  $C_H$  are incorporated so that the balance operation of the bridge is insensitive to the offset voltage and the finite open-loop gain of op-amp  $A_1$  [13].  $\phi$  and  $\bar{\phi}$  are the nonoverlapping two phase clocks for driving the analog switches involved in the bridge. Capacitor  $C_M$  is incorporated to prevent the spikes which would otherwise be generated by op-amp  $A_1$  in the nonoverlapping period [14]. This capacitor has, however, no effect upon the bridge balance operation and is thus neglected henceforth.

Comparator  $A_2$  compares the bridge output  $V_o$  with the reference voltage  $V_R$ , to inform the microcomputer of the present state of the bridge. Depending on the comparator output "Q", the microcomputer produces clock signals  $\phi_1$  and  $\phi_2$  which control switches  $M_1$  and  $M_2$ , respectively, to balance the bridge digitally. The logic expressions for  $\phi_1(n)$  and  $\phi_2(n)$  in the  $n$ th cycle of the two phase clock are given by

$$\phi_1(n) = \overline{Q(n-1)} + \phi(n) \quad (1)$$

$$\phi_2(n) = Q(n-1) \cdot \bar{\phi}(n) \quad (2)$$

where  $Q(n-1)$  denotes the logic level of the comparator output in the preceding clock cycle. The operation of the interface will now be described in more detail.

The timing diagram of the clock signals and the output voltage waveform of the capacitance bridge are depicted in Fig. 5. To begin with, the microcomputer outputs a reset pulse  $\phi_R$  in synchronism with the  $\phi$  clock signal to initialize the bridge. The output voltage of op-amp  $A_1$  is  $V_R$ . Thus, in this reset phase,  $C_C$  and  $C_F$  are charged to  $V_R$ , while  $C_X$ ,  $C_S$ , and  $C_R$  are charged to  $V_X$ ,  $V_S$ , and  $V_R$ , respectively, with the polarity indicated in Fig. 4. Because  $C_C$  is charged to  $V_R$ , the node  $A$  can be regarded as the virtual ground terminal of op-amp  $A_1$  [13]. Let us assume that the comparator output in the previous measurement cycle is "1". Then, in the next  $\bar{\phi}$  phase,  $\phi_2$  becomes "1" and the charge  $Q_R = C_R V_R$  stored in  $C_R$  is transferred, (together with the charges  $Q_X = C_X V_X$  and  $Q_S = C_S V_S$  stored in  $C_X$  and  $C_S$ , respectively) into  $C_F$  to charge it with the polarity indicated. The net charge accumulated in  $C_F$  by this process is

$$Q_{acc} = Q_R + Q_S - Q_X. \quad (3)$$

Since the dc voltages  $V_R$ ,  $V_S$ , and  $V_X$  are chosen such that  $Q_{acc}$  be positive, the charge accumulation in this phase increases the bridge output  $V_o$  by  $Q_{acc}/C_F$  and the comparator output "Q" becomes "0". In the  $\phi$  phase of the next cycle,  $C_R$ ,  $C_S$ , and  $C_X$  are charged again to their own voltages. In the next  $\bar{\phi}$  phase,  $C_X$  and  $C_S$  are discharged to transfer their charges to  $C_F$ , while  $C_R$  remains charged because the switch  $M_2$  is kept "off". Since the voltages  $V_X$  and  $V_S$  are chosen such that  $Q_X > Q_S$ , the charge

$$Q_{ext} = Q_X - Q_S \quad (4)$$

is extracted from  $C_F$  by this process and the output voltage of the bridge decreases by  $Q_{ext}/C_F$ , as shown in Fig. 5. This charge extraction continues until the comparator out-

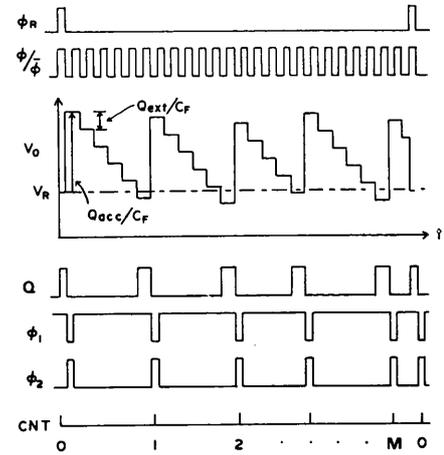


Fig. 5. Timing diagram and the output voltage waveform of the capacitance bridge.

put "Q" becomes "1" and the charge  $Q_{acc}$  is accumulated again into  $C_F$ . Repeating the above process of the charge accumulation and extraction for  $N$  cycles of the two-phase clock until the next reset pulse  $\phi_R$  initializes the bridge, the microcomputer counts the number of times the charge  $Q_{ext}$  is extracted.

Let the count be  $M$ . Then, the total charge accumulated into  $C_F$  is  $MQ_{acc}$ , while that extracted from  $C_F$  is  $(N - M)Q_{ext}$ . Therefore, the bridge output  $V_o(N)$  at the end of one measurement cycle is

$$V_o(N) = V_R + [MQ_{acc} - (N - M)Q_{ext}]/C_F. \quad (5)$$

Referring to Fig. 5, one notices that the bridge output is always in the range from  $V_R - Q_{ext}/C_F$  to  $V_R + Q_{acc}/C_F$ . Thus, we can obtain the relation

$$M/N - (Q_X - Q_S)/Q_R < 1/N = 1 \text{ LSB}. \quad (6)$$

The capacitance  $C_X$  of the humidity sensor can be represented as

$$C_X = C_o(1 + S_d \cdot \text{RH}) \quad (7)$$

where  $C_o$  is the offset capacitance and  $S_d$  denotes the "dielectric sensitivity" of the sensor. Adjusting  $V_S$  and  $V_R$  such that  $C_o V_X = C_S V_S$  and  $C_o V_X S_d = C_R V_R$  hold, respectively, and setting  $N = 2^n$ , one can obtain, from (6), the  $n$ -bit binary representation of RH

$$\text{RH} = M/2^n = m_1 2^{-1} + m_2 2^{-2} + \dots + m_n 2^{-n}. \quad (8)$$

Figure 6 shows the flowchart of the control subroutine. The subroutine uses the "DE" pair register for counting the number  $N$  of the two-phase clock cycle and the "HL" pair register for counting  $M$ . After resetting these registers, the program enters the  $\bar{\phi}$ -state. In this state, the  $\phi$ ,  $\phi_1$ , and  $\phi_R$  clocks are first reset to "0", and then, after  $5.4 \mu\text{s}$ ,  $\bar{\phi}$  and  $\phi_2$ , if "Q" = "1", clocks are set to "1" and outputted to the bridge from port C. The  $\bar{\phi}$  clock lasts for  $22.5 \mu\text{s}$  until it is reset to "0" in the  $\phi$ -state. Incrementing the "DE" register and then sensing the output level "Q" of comparator  $A_2$ , the program completes the operation in the  $\bar{\phi}$ -state.

In the  $\phi$ -state, the program first resets  $\phi$ ,  $\phi_1$ , and  $\phi_2$  clocks. Thus, all the clocks are "off" until the  $\phi$  and  $\phi_1$



The direct reading of RH on the display requires

$$(C_o + C_p)V_X + Q_f = C_S V_S \quad (19)$$

$$C_o S_d V_X = C_R V_R. \quad (20)$$

To meet the above conditions for the offset cancellation and the sensitivity adjustment, two-point calibration is obliged; first, the reading  $m_1$  when the humidity sensor is exposed to the atmosphere of some reference humidity  $RH_1$  is noted. Then, expose the sensor to the atmosphere of different humidity  $RH_2$ . Watching the reading  $m_2$ , adjust the reference voltage  $V_R$  such that  $m_2 - m_1$  coincides with  $RH_2 - RH_1$ . This establishes the sensitivity condition (20). Next, adjust the voltage  $V_S$  such that  $m_2$  coincides with  $RH_2$ . This establishes the offset cancellation condition (19).

The readings of the hygrometer thus calibrated are indicated on the right-hand ordinate of Fig. 2 for the humidity cycle from 20 to 90 percent. Because the calibration eliminates the errors caused by the nonideal factors involved in the interface and compensates the deviations of the offset capacitance and the sensitivity of the humidity sensor, the error of this hygrometer is solely determined by the temperature dependence and the long-term drift of the sensor and is estimated, from data in Figs. 2 and 3, to be less than 2 percent.

## V. CONCLUSIONS

A digital hygrometer using the polyimide capacitive humidity sensor is described. The switched-capacitor interface for detecting the capacitive change of the sensor and converting it into the digital number is very simple and requires no component matching and trimming. Therefore, a low cost and compact "smart humidity sensor" can be realized by integrating the hygroscopic film and the interface circuit onto a single Si chip.

The accuracy of the present hygrometer is limited to 2 percent by the temperature dependence and the long-term drift of the humidity sensor. The temperature compensa-

tion can be easily accomplished by the software because the one-chip microcomputer accommodates the analog-to-digital converter available for converting the voltage across a temperature sensor such as a junction diode or a thermister into the digital number. This will allow the indication of the temperature-humidity index as well as the improvement of the RH measurement accuracy.

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